

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

**In re application of:**

SUH, Nam P. et al.

**Application No.:**

10/029,158

**Filed:**

December 21, 2001

**For:**

Apparatus and Method for Chemical  
Mechanical Polishing of Substrates

**Examiner:**

Maurina T. Rachuba

**Art Unit:**

3723

**Confirmation No.:**

5210

**Date:** December 13, 2005

Mail Stop PETITION

Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

**PETITION FOR CHANGE IN ORDER OF INVENTORS**

Sir:

In accordance with MPEP § 605.04(f) and under the provisions of 37 C.F.R. § 1.182, Applicants hereby petition to change the order of names of the joint inventors of the above-identified application. Specifically, Applicants request that the order of inventors' names be changed to the following order:

- 1.) Jason Melvin;
- 2.) Nam P. Suh; and
- 3.) Hilario L. Oh

Accompanying this petition is a check in the amount of \$130.00 to cover the petition fee as set forth in 37 C.F.R. § 1.17(h).

The Commissioner is hereby authorized to charge any underpayment of the following fees associated with this communication, including any necessary fees for extension of time and for the presentation of extra claims, or credit any overpayment to Deposit Account No. 50-2319 (Our Order No. A-69175-1/MSS (463035-650)).

12/16/2005 SFELEKE2 00000085 10029158

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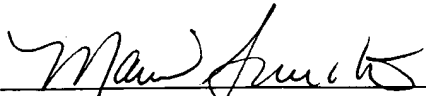
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PATENT

Attorney Docket No. A-69175-1/MSS (463035-650)  
U.S. Serial Application No. 10/029,158

Respectfully submitted,

Date: December 13, 2005

By:   
Maria S. Swiatek, Reg. No. 37,244

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